

CLAIMS

1. A substrate inspection apparatus for inspecting a formation state of a pattern area formed on a substrate, the substrate inspection apparatus comprising:

an inspection data generation means for generating inspection data in the inside and outside of a pattern area to be inspected; and

a determination means for determining whether the pattern area is defective or not defective by comparing the inspection data of the inside of the pattern area generated by the inspection data generation means with predetermined inside reference inspection data and comparing the inspection data of the outside with predetermined outside reference inspection data.

2. The substrate inspection apparatus according to Claim 1, wherein the type of the inspection data of the inside of the pattern area differs from the type of the inspection data of the outside.

3. The substrate inspection apparatus according to Claim 1, wherein the inspection data of the inside of the pattern area is data about luminance and the inspection data of the outside is data about shapes.